

IN THE CLAIMS:

Kindly cancel ~~claims~~ 134-136 without prejudice or disclaimer.

Kindly amend claims 137 and 144 as follows:

--¹~~137~~. (Amended) A method of preparing an electron-emitting device, comprising the steps of:

g1
forming electrodes opposed to each other on a substrate;

forming between the electrodes ^{and in contact therewith} an insulating layer in which fine particles are completely enclosed; and

etching the insulating layer so as to partially expose the fine particles.

[introducing fine particles into an insulating layer, said fine particles being enclosed in the insulating layer so as to partially expose said fine particles.]--

--²~~144~~. (Amended) A method of preparing an electron-emitting device comprising the steps of:

g2
forming electrodes opposed to each other on a substrate;

forming between the electrodes ^{and in contact therewith} a semiconductor layer in which fine particles are completely enclosed; and

etching the semiconductor layer so as to partially expose the fine particles.